



Tool Make & Model

AMAT - CENTURA

Tool Configuration / Specifications

DPS plasma etch system

Does not include: Pumps, chillers, abatement, HP robot, endpoint unit

Process: DPS

Fab section: Etch

Software version: E4826

CIM: SECS/GEM

Main system:

PDU/AC rack

VME controller system

Centura platform

(Qty 2) DPS etch chambers

Factory interface:

(Qty 2) Open cassettes

Handler system:

HP robot: None

On-the-fly sensor: Installed

(Qty 2) Tilt-out cassettes

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